

WHAT IS CLAIMED IS:

1. A semiconductor manufacturing apparatus comprising:

a main unit for processing raw materials and forming a semiconductor;

recording means for recording as predetermined data information of an operation to be executed by said main unit;

operating means for operating the operation of said main unit through the use of said predetermined data and simulating said operation; and

display means located remotely from said main unit and for displaying said simulated result.

2. A diagnosis apparatus of a semiconductor manufacturing apparatus being characterized to be connected with recording means in which the information of an operation to be executed by said semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor through communicating means and have display means located remotely from said semiconductor manufacturing apparatus and for displaying the simulated result given by operating means for operating the operation of said semiconductor manufacturing apparatus for simulating said operation.

3. A program for a semiconductor manufacturing apparatus comprising the steps of:

receiving from a supplier of supplying information of an operation to be executed by the semicon-

ductor manufacturing apparatus for processing raw materials and forming a semiconductor as predetermined data said data through communicating means;

displaying a simulated result supplied by operating means for operating the operation of said semiconductor manufacturing apparatus and simulating said operation by said data; and

transmitting said result to said supplier.

4. An operating system for a semiconductor manufacturing apparatus comprising:

means for receiving from a supplier of supplying information of an operation to be executed by the semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor as predetermined data said data through communicating means;

display means for displaying a simulated result supplied by operating means for operating the operation of said semiconductor manufacturing apparatus and simulating said operation by using said data; and

wherein said data is received in response to a request given from a user of said semiconductor manufacturing apparatus and a diagnosed result of said semiconductor manufacturing apparatus based on said simulated result is supplied to the user of said semiconductor manufacturing apparatus.

5. A semiconductor manufacturing apparatus as claimed in claim 1, wherein said data includes the

information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

6. A diagnosis apparatus of a semiconductor manufacturing apparatus as claimed in claim 2, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

7. A program for a semiconductor manufacturing apparatus as claimed in claim 3, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

8. An operating system for a semiconductor manufacturing apparatus as claimed in claim 4, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.